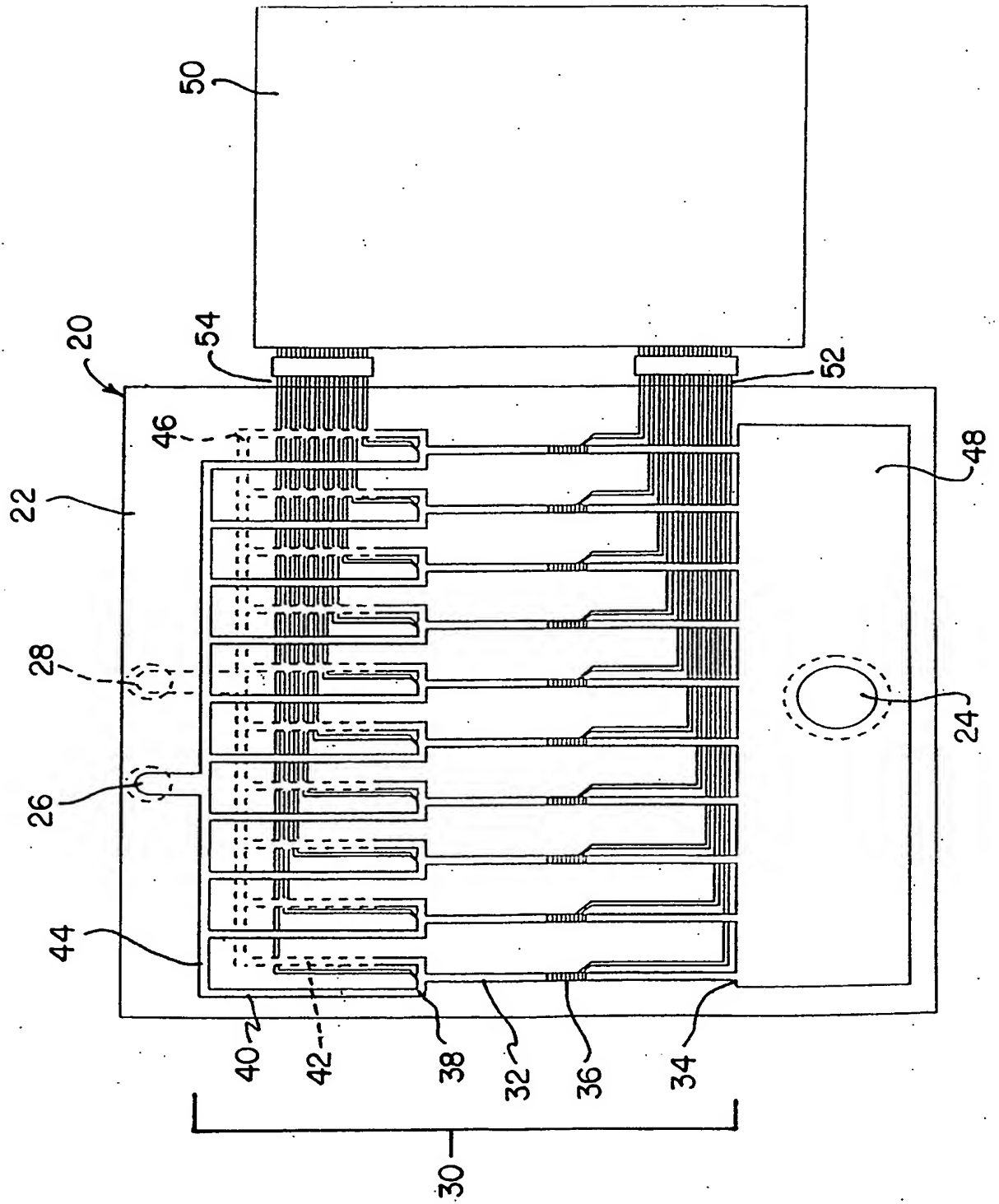


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FIG. 1



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FIG. 2

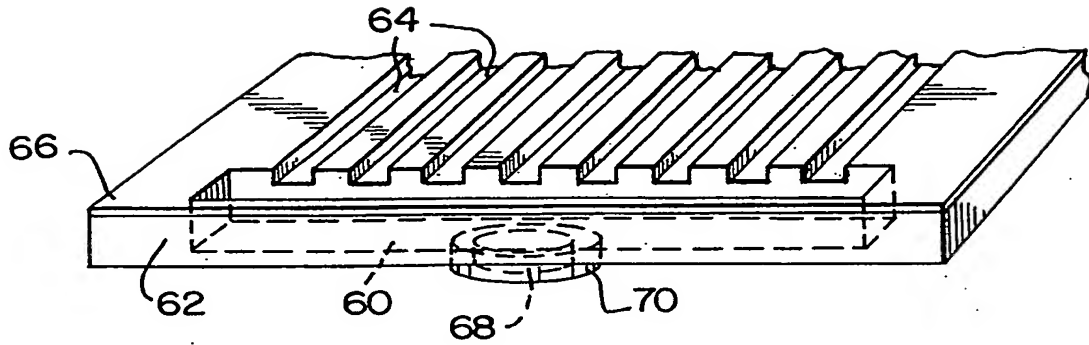


FIG. 3A

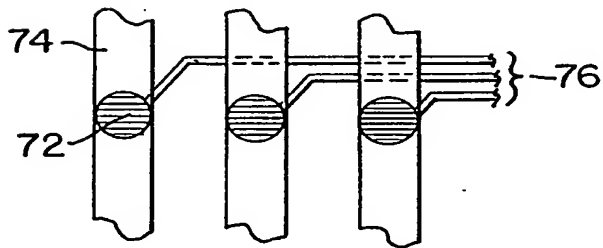


FIG. 3B

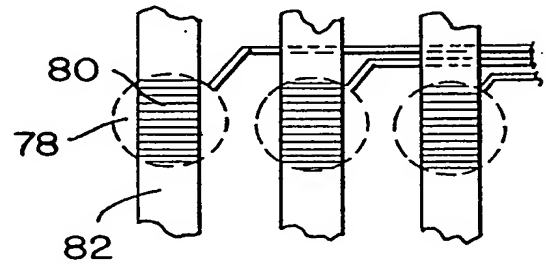
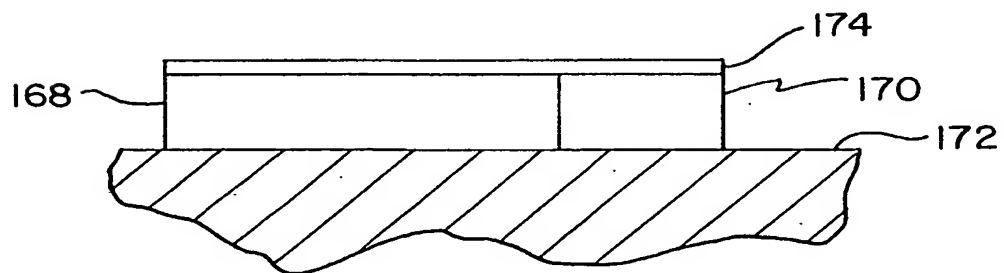


FIG. 4A



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FIG. 4B

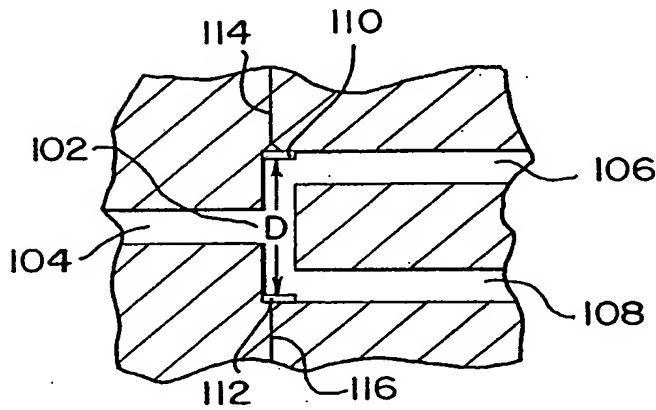
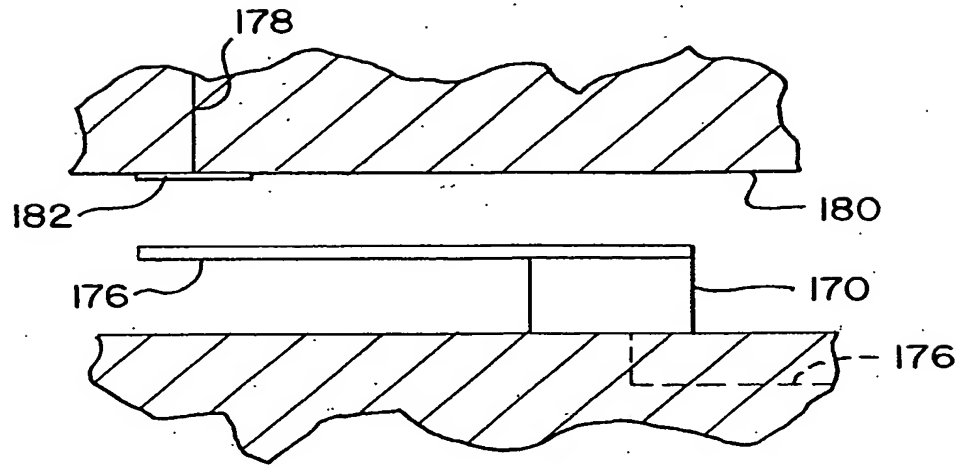
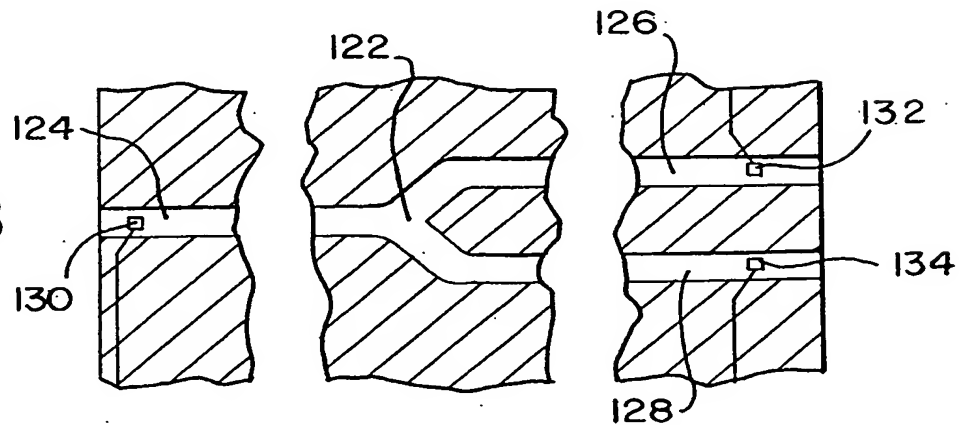


FIG. 5A

FIG. 5B



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FIG. 5C

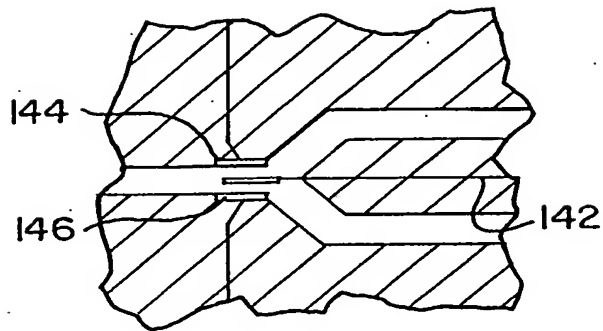


FIG. 5D

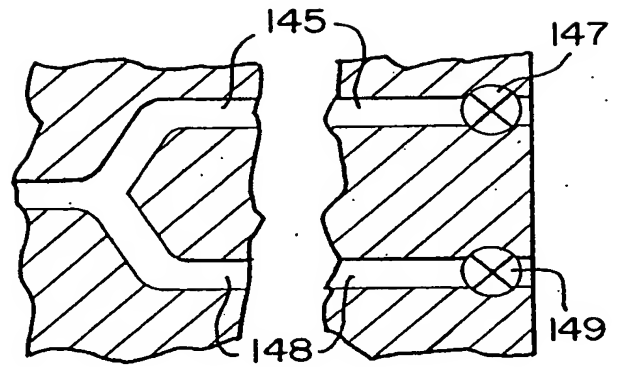
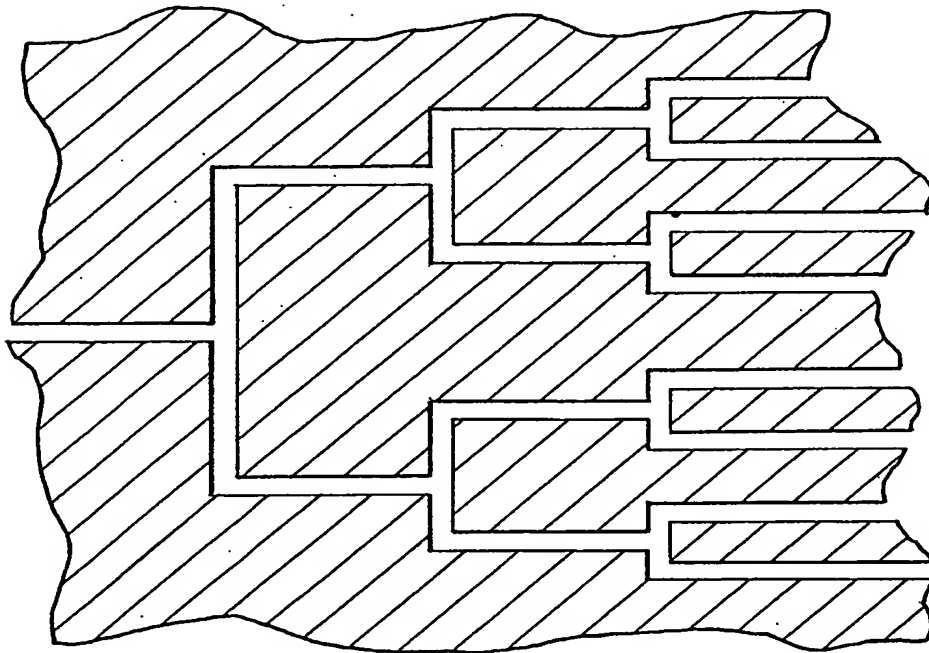


FIG. 6



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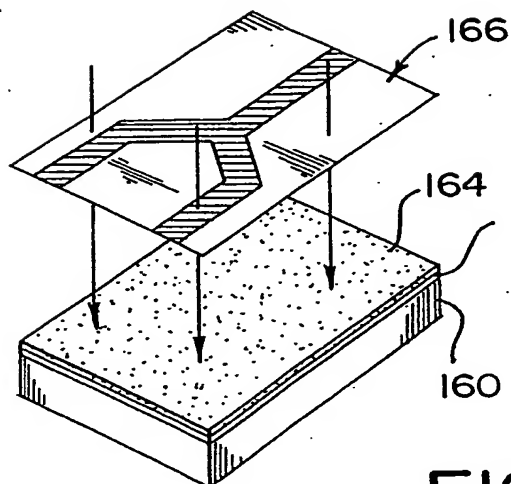
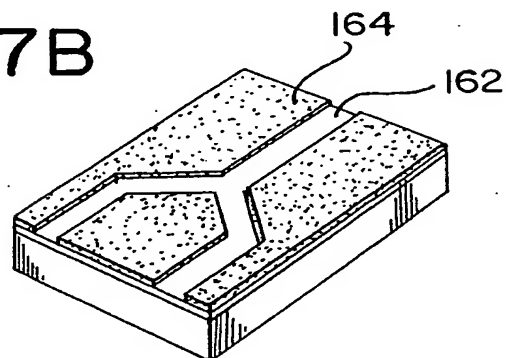


FIG. 7A

DEVELOP  
& RINSE

TO  
FIG. 7B

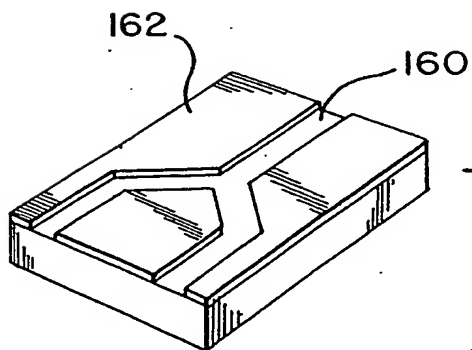
FIG. 7B



TO  
FIG. 7C

1. ETCH  $\text{SiO}_2$   
2. REMOVE  
RESIST

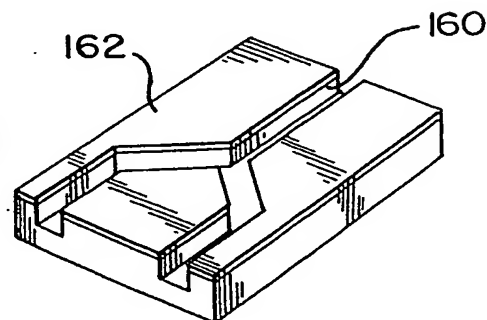
FIG. 7C



ETCH Si

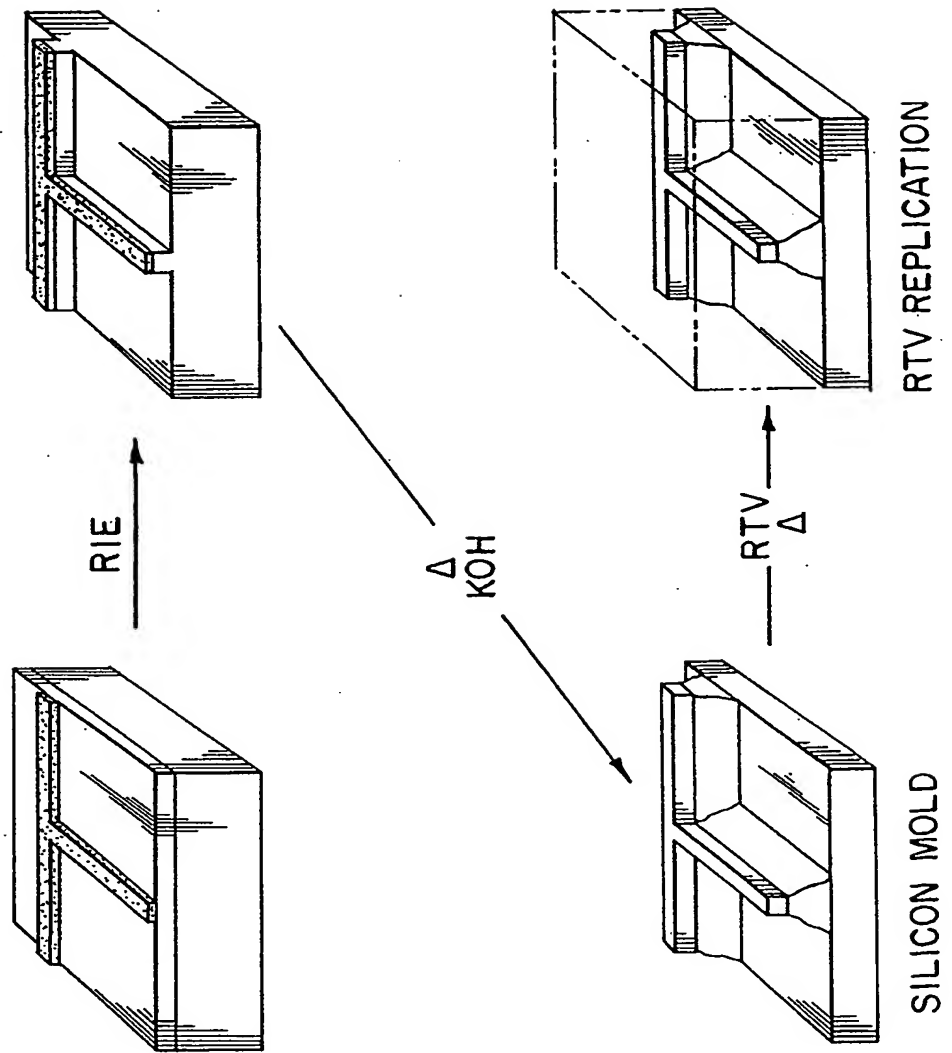
TO  
FIG. 7D

FIG. 7D



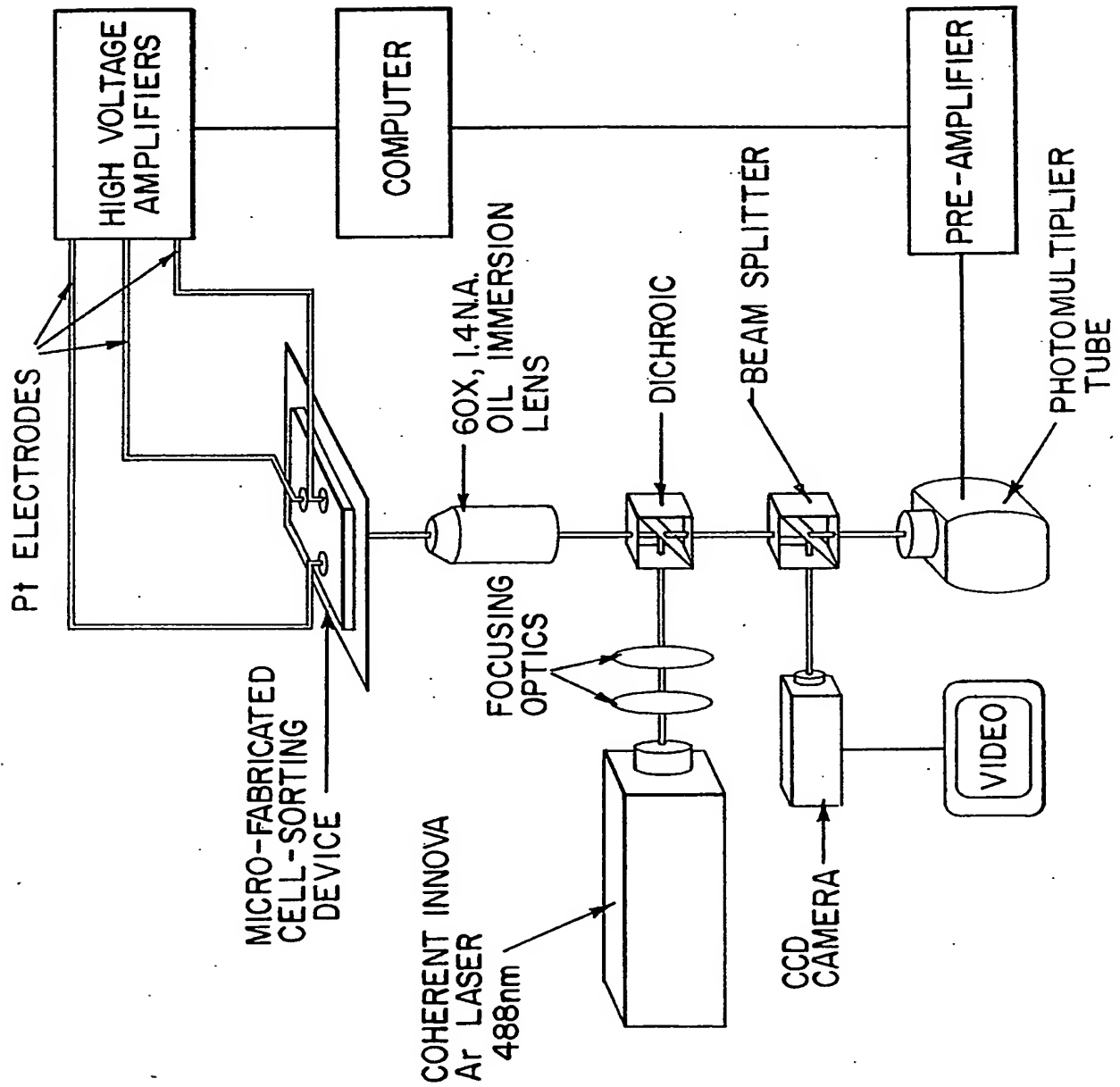
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FIG. 8



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FIG. 9



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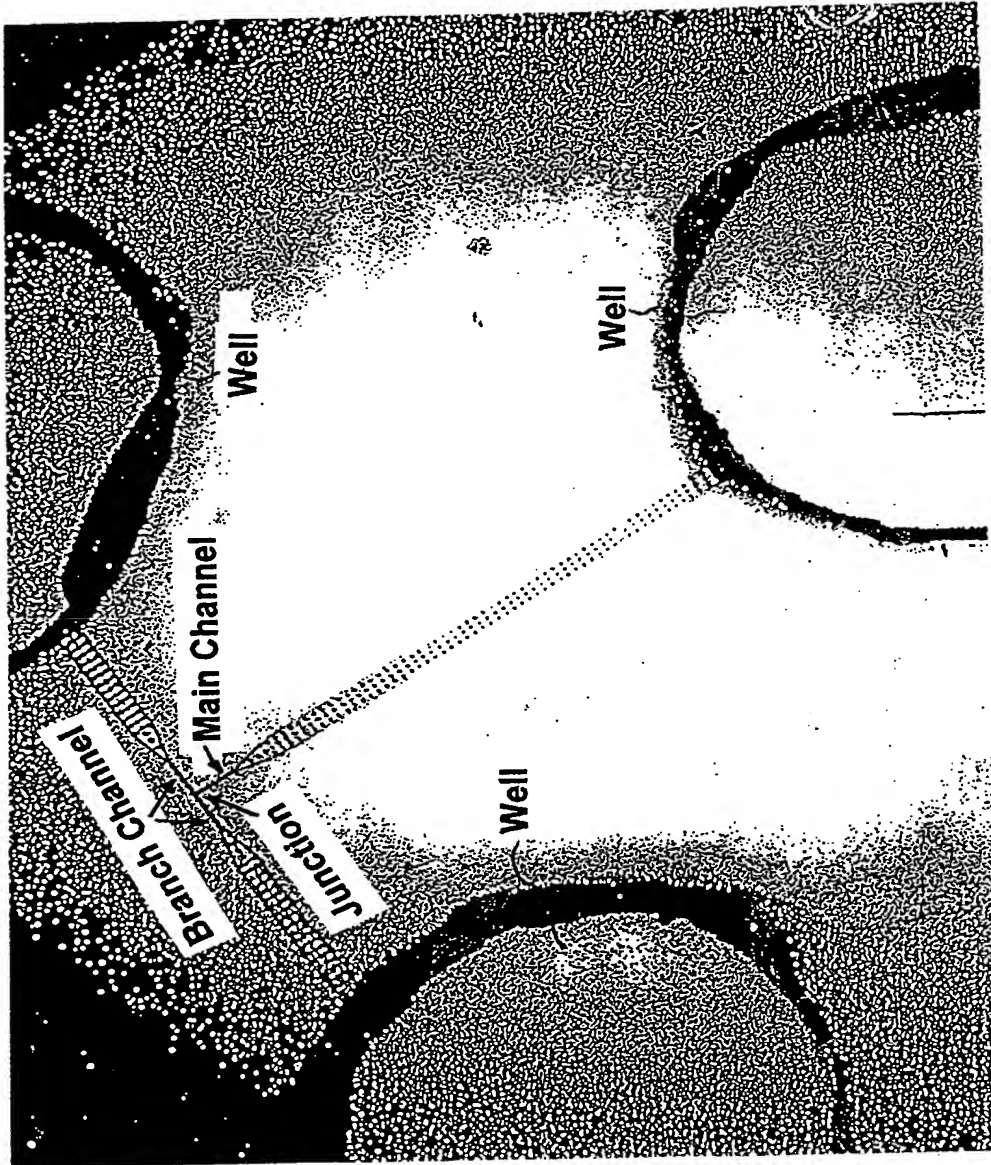


FIG. 10



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FIG. IIA

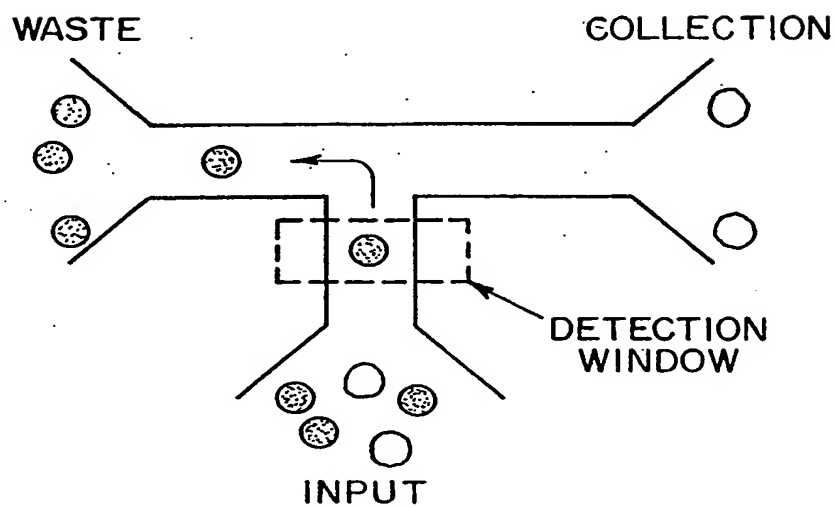
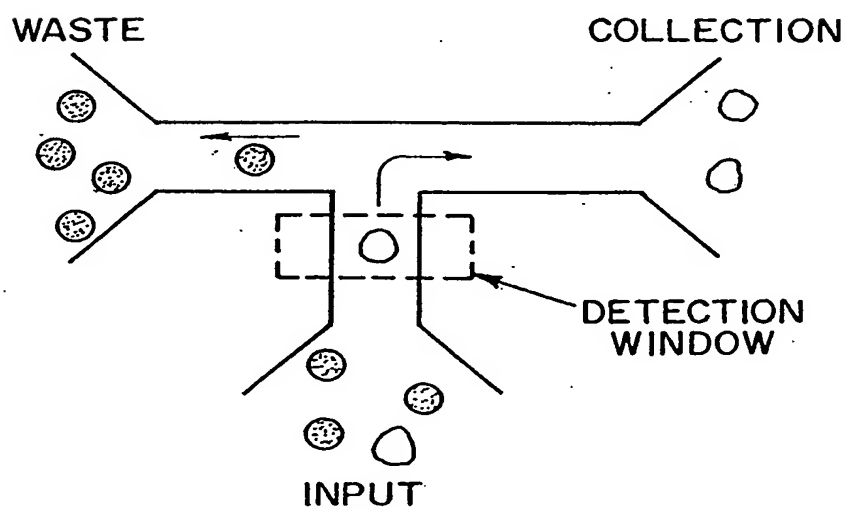


FIG. IIB



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FIG. 12A

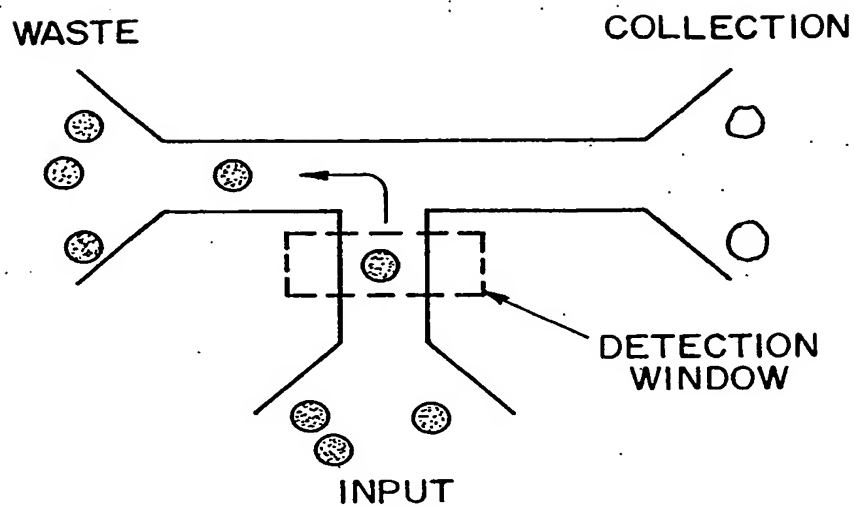
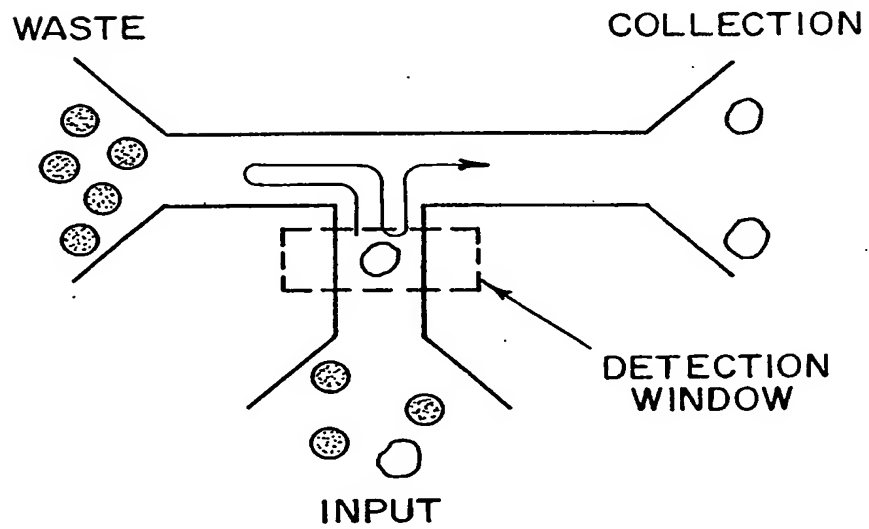
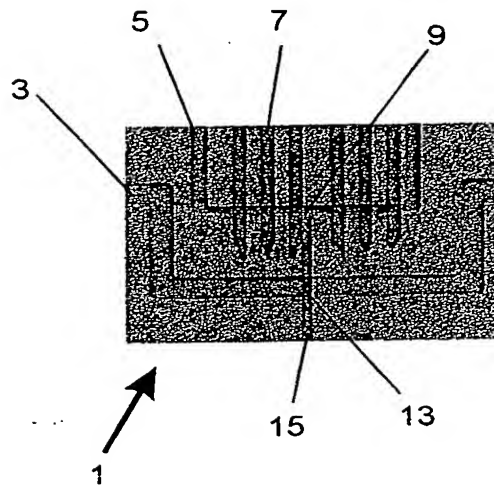


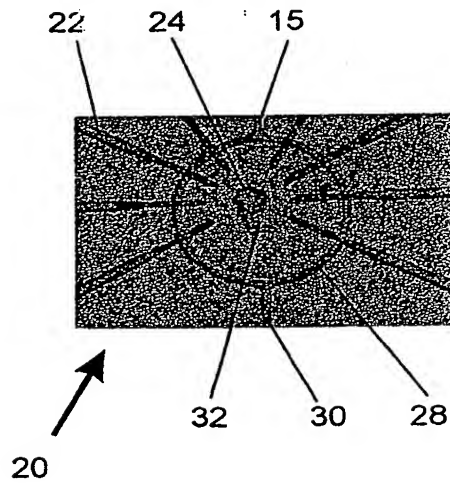
FIG. 12B



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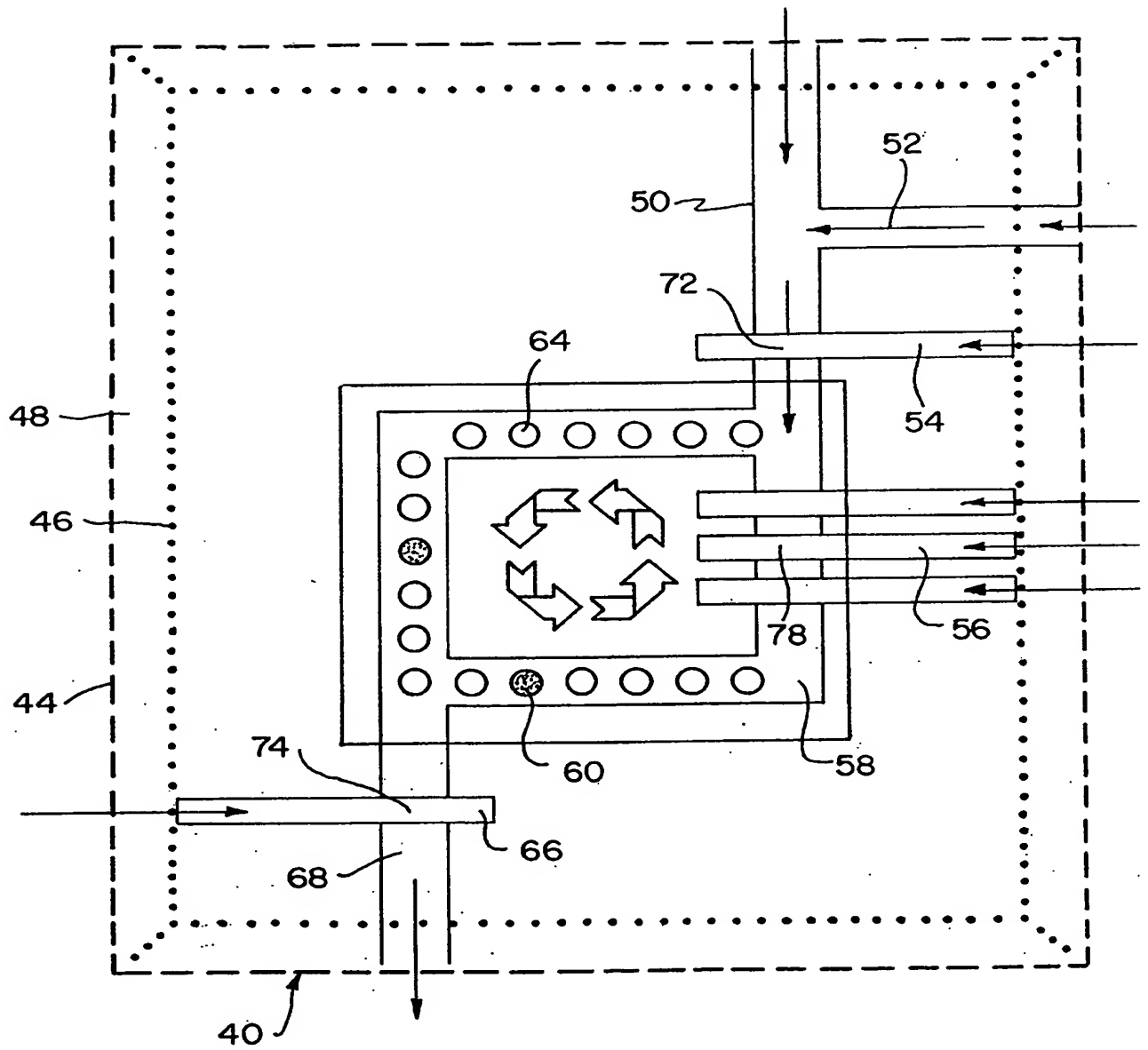
**FIG. 13A**



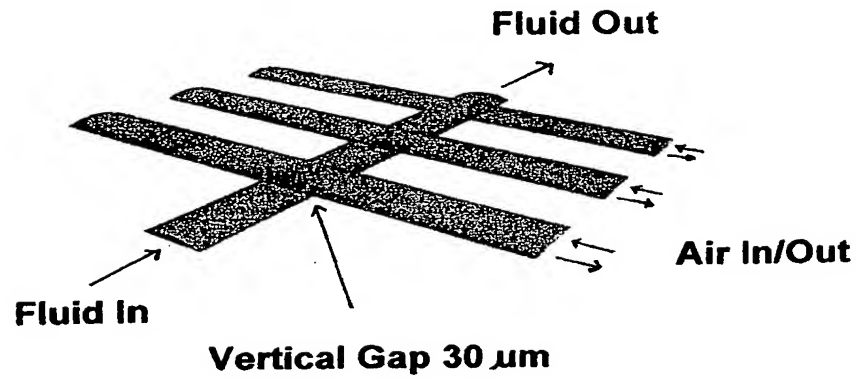
**FIG. 13B**

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FIG. 14



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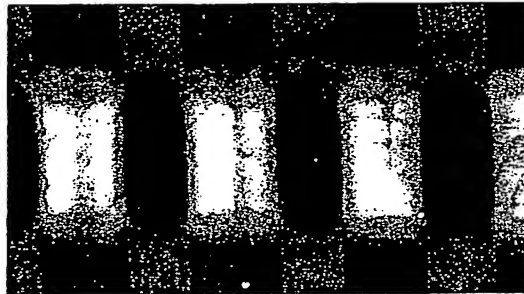


**FIG. 15**

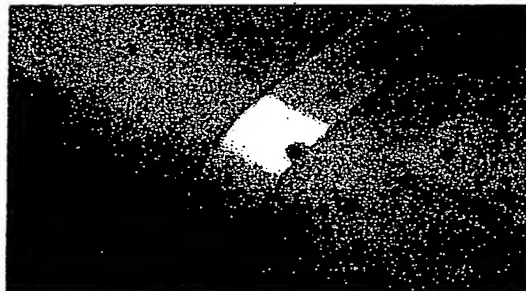


**FIG. 16A**

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**FIG. 16B**



**FIG. 16C**

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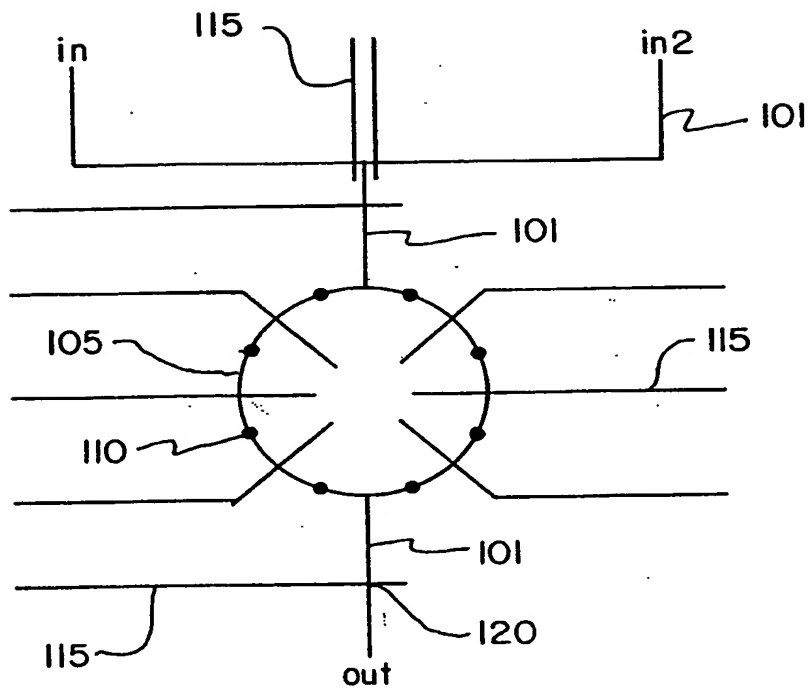
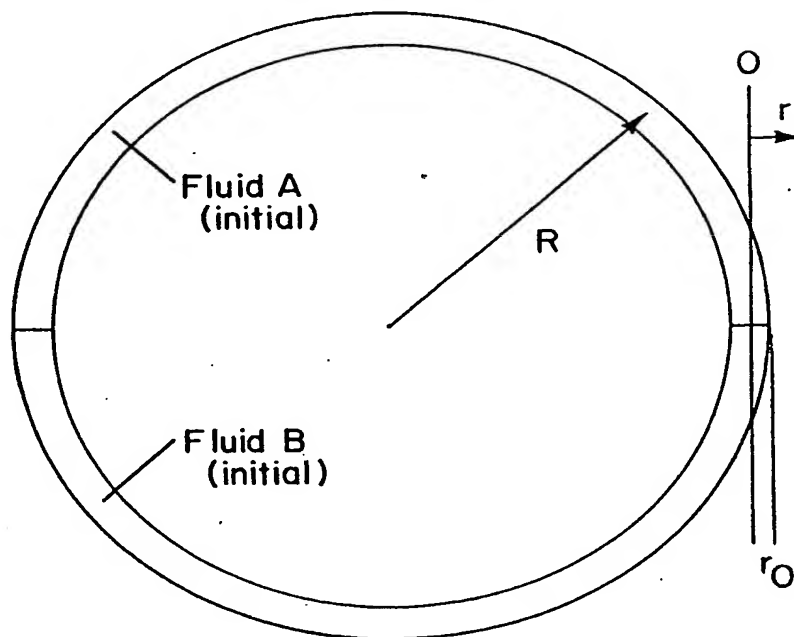
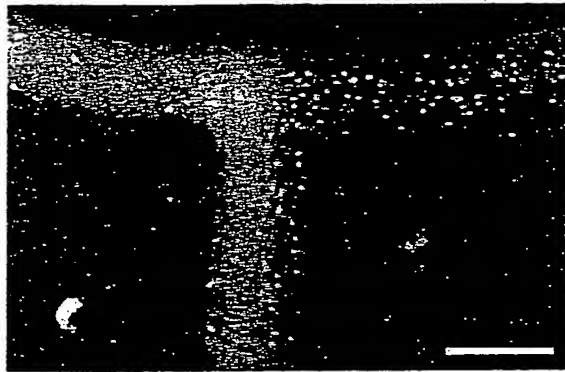


FIG. 17

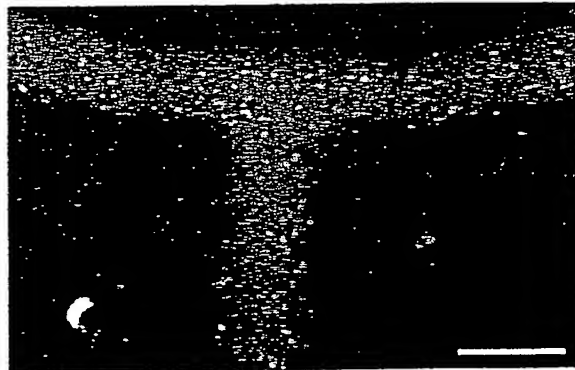
FIG. 24



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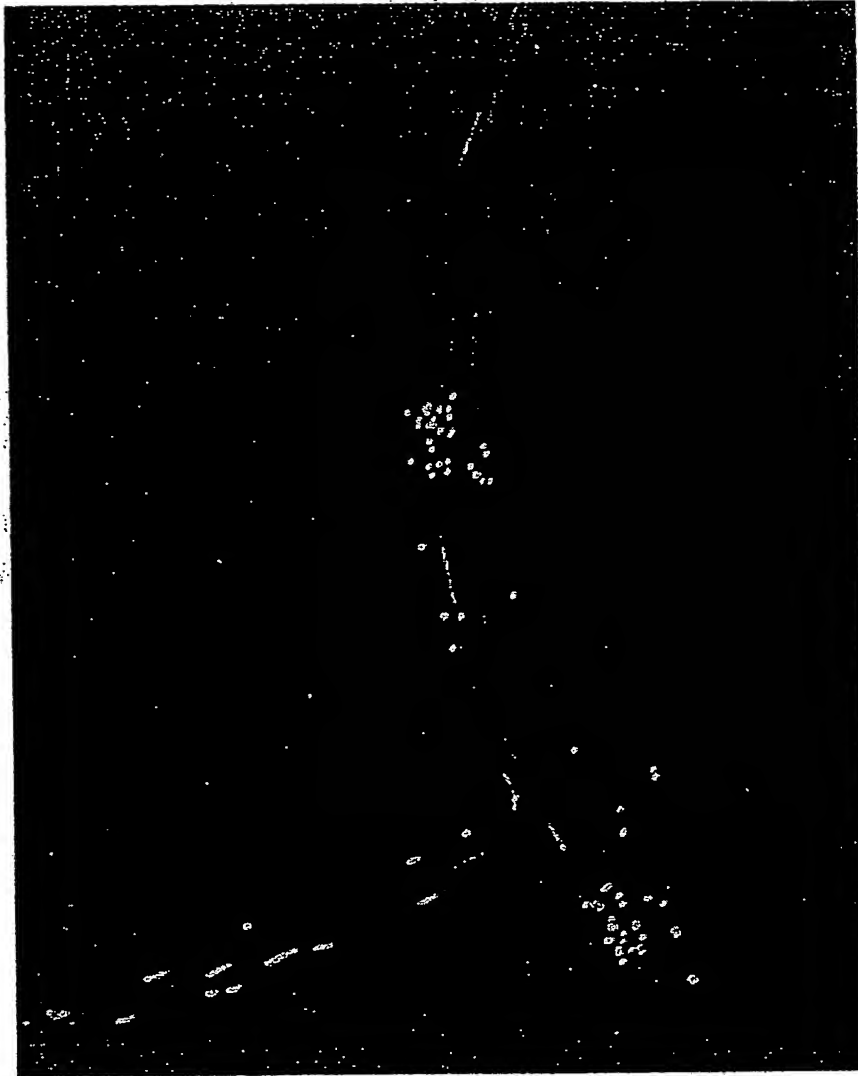
**FIG. 18A**



**FIG. 18B**



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**FIG. 19**

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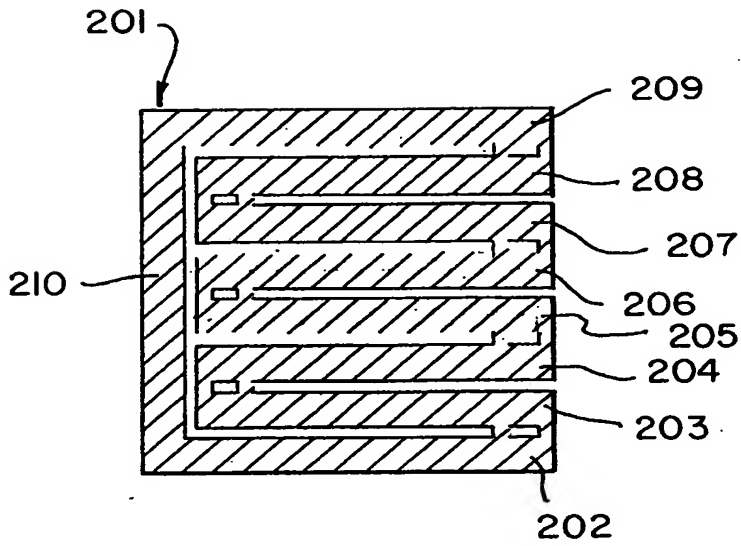


FIG. 20

FIG. 21A

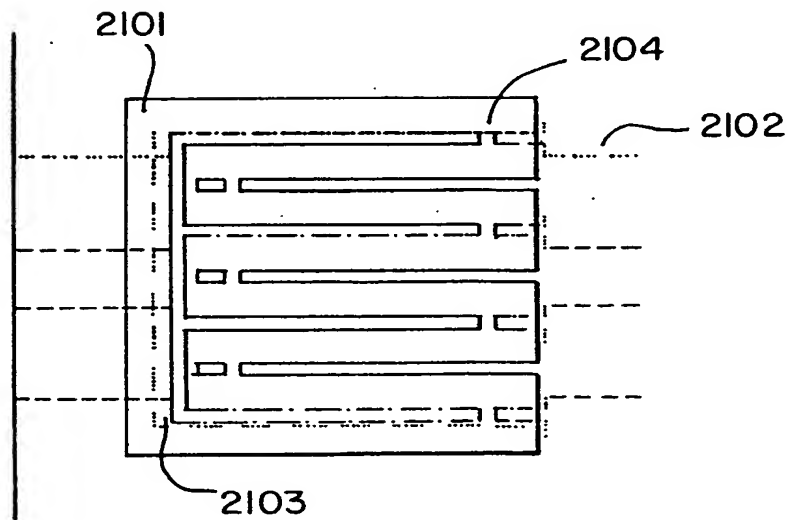
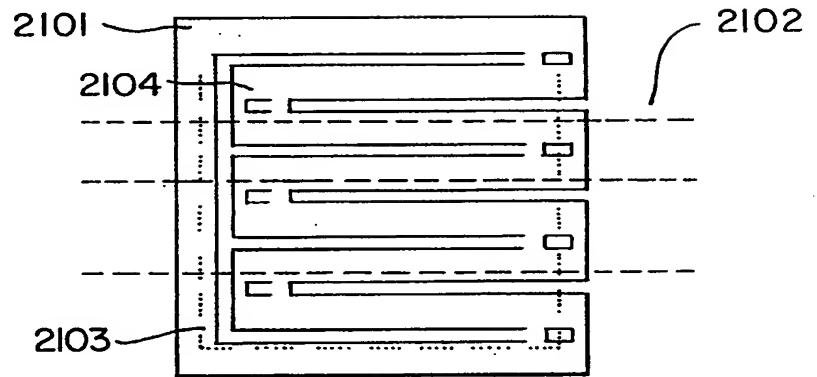
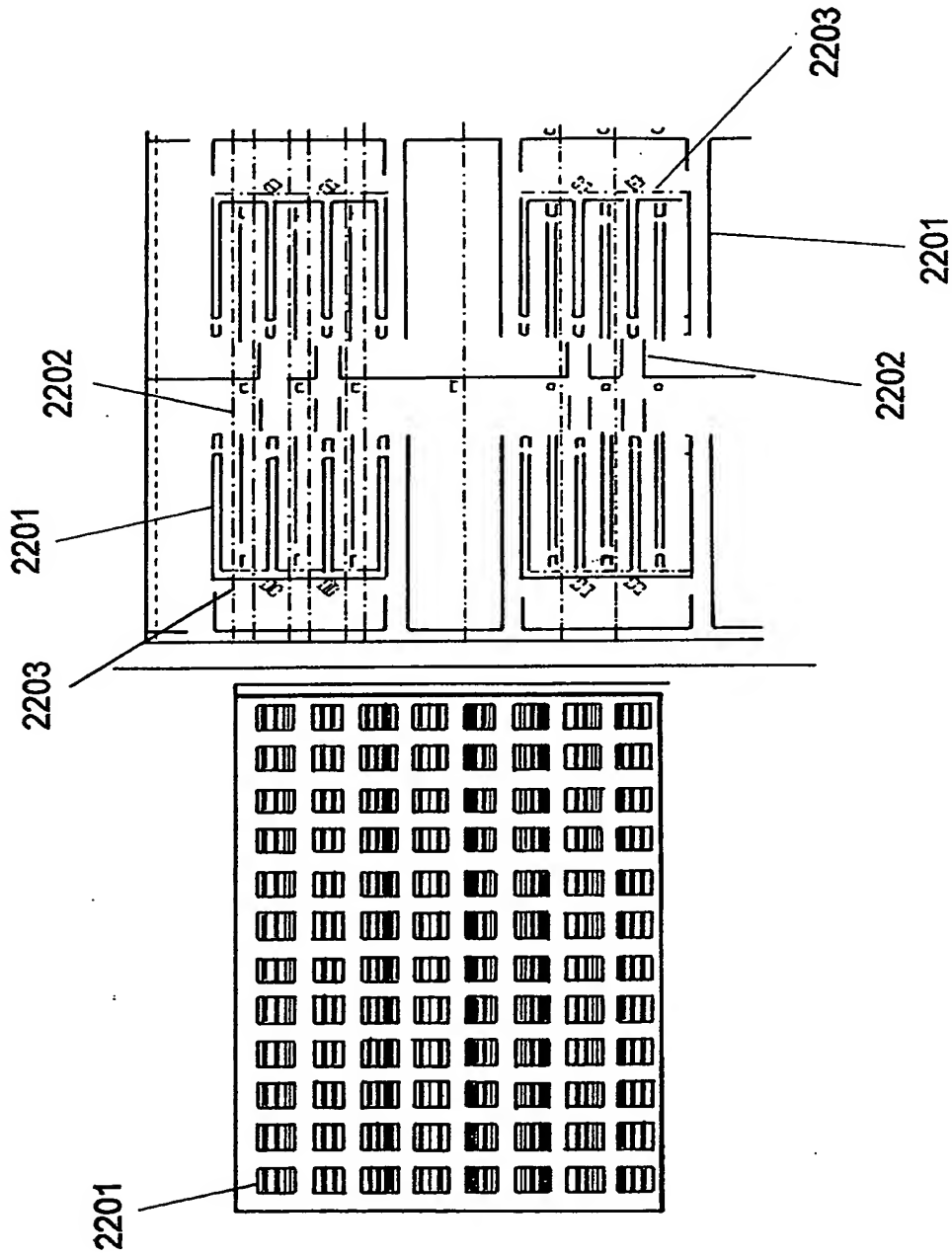


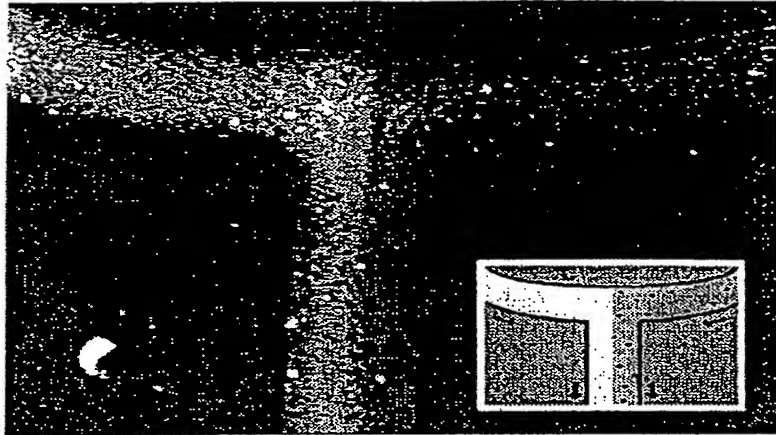
FIG. 21B



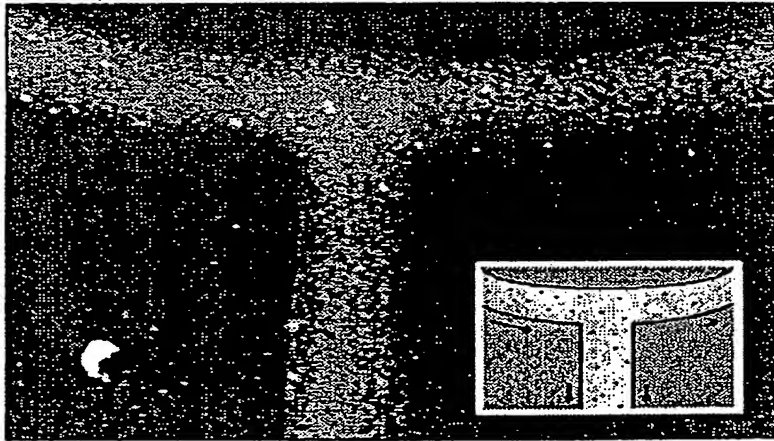
**FIG. 22B**

**FIG. 22A**

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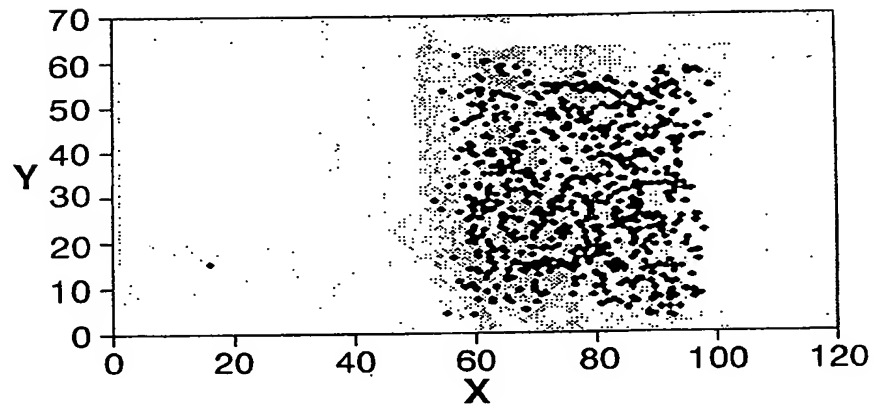
**FIG. 23A**



**FIG. 23B**

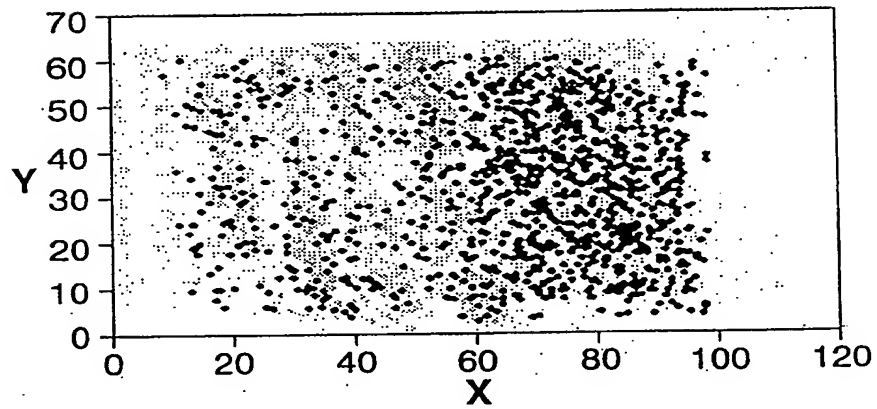
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**Normal Flow**



**FIG. 23C**

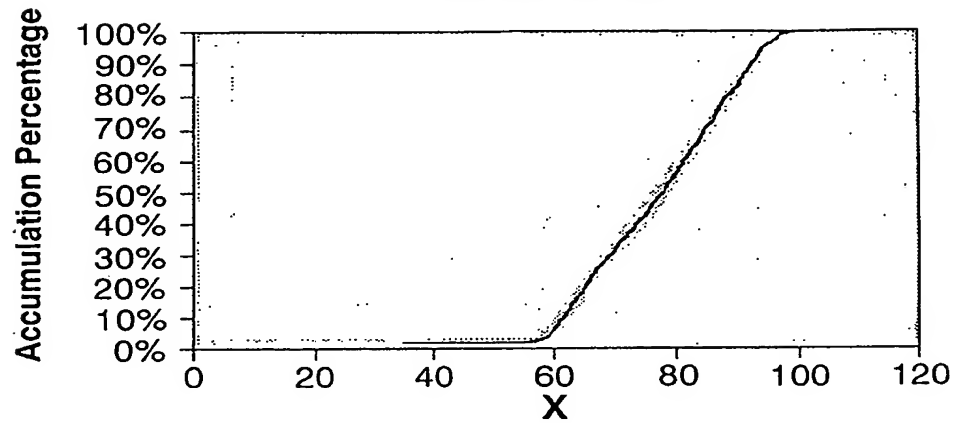
**Rotary Mixing (30Hz, 40kPa)**



**FIG. 23D**

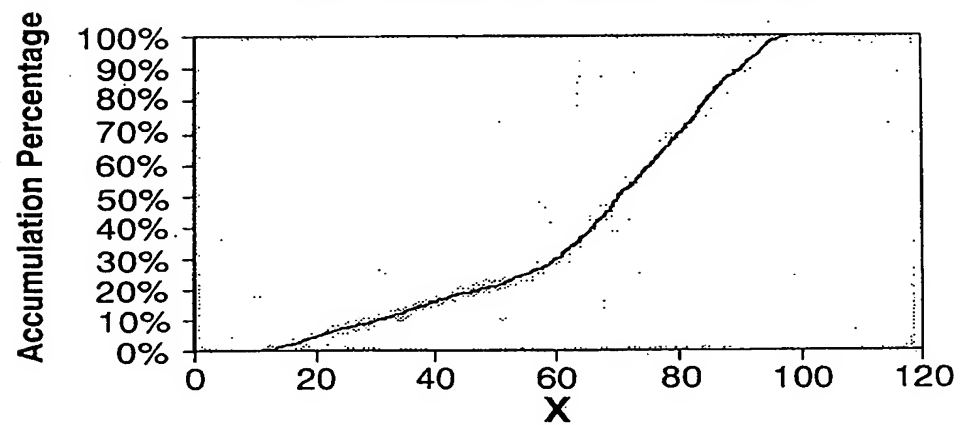
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**Accumulated X Distribution  
Normal Flow**



**FIG. 23E**

**Accumulated X Distribution  
Rotary Mixing (30Hz, 40kPa)**



**FIG. 23F**